

AMENDMENTS TO THE SPECIFICATION:

Please amend the paragraph beginning at page 9, line 16 as follows:

Fig. 3 a ~~bottom~~ top view a portion of Fig. 1 including illustrating the wafer, the arms, and the grippers of the arms,

Please amend the paragraph beginning at page 12, line 16 as follows:

The upper leg 115a of the arm 107a has been inserted into or extends through the opening 102a of the housing 102, and is moveably attached to the fulcrum 114a of holding arm 110a of the support structure 110 to form a lever apparatus, which allows the upper leg 115a under defined circumstance, which will be described hereinafter, to change its angle with respect to the horizontal line and the holding arm 110a respectively. The upper leg 115a with its end inside of the FSS-1 housing 102 has a roller 108a rotatably fixed at its end, whereby the roller 108a is supported by the second topography 103a of the rotating plate 104. The upper leg 115a, and thus the support structure arm 110a too, is held down or pushed against to the contour circles 104a or cam structure 103a with the spring 109a. For this purpose the spring 109a is fixed to the upper leg ~~[[116a]]~~ 115a and the bottom part of the housing 102 at a point between the roller 108a and the bearing fulcrum 114a depending on the force to be excerpted on to the upper leg 115a and the contour profile 103a, respectively.

Please amend the paragraph beginning at page 16, line 24 as follows:

The elevation contrivance or device 202 encompasses a rectangular base plate to which an actuator 205 centrally is attached. At the front end corners of the base plate 204, the base plate 204 comprises through holes for attaching the base plate. The actuator 205 is a linear actuator, which has a spindle 216 at one side. For to accommodate actuator 205 on the base plate 204, base plate 204 further comprises a centrally positioned through whole, through which the actuator spindle 216 extends. It is the function of the elevation contrivance 202 to elevate manipulator drive 203 in a direction perpendicular to a plan defined by the movement of the arms 207a and 207b. Therefore the elevation contrivance 202 is affixed to the top side of the housing 227 of

the manipulator drive 203 via its spindle 216 and linear guides 210 (linear guide 210a to the right side and linear guide 210b to left side of the actuator). The linear guides 210a, 210b consist of a pin 212 (212a and 212b) (Fig. 9) and a guide 211 (211a and 211b) which guide the elevation movement. The pins 212 are symmetrically arranged with respect to the linear actuator 205 and extend through respective holes, which are comprised by the base plate 204. Pins 212 are attached to base plate by guide clamps 206 (206a and 206b), and co-operate with the guides 211, which are affixed to the top surface of housing 227 by means of flanges. Thus actuator 205, with its spindle, can move the housing 227 of manipulator drive 203 up and down if the actuator is appropriately charged by current via cable 214. On the front side of housing 227, in central position on the front, a holder 213 is attached to the housing 227, which carries a scanning sensor 226 that detects or checks the presents of wafer 215, i.e. it detects whether the arms 207 bear a wafer or not. The sensor 226 is fastened to the free end of holder 213, whereby the holder extends from housing 227 such that at least wafers or disks with two different diameters, for instance of 200mm and 300mm, can be detected.